

INFORMATION DISCLOSURE CITATION

Atty. Docket No.	02887.0208	Serial No.	09/920633
Applicant	Osamu NAGANO et al.		
Filing Date	August 3, 2001	Group:	2853

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U.S. PATENT DOCUMENTS

Examiner Initial*		Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
LN	A	4,075,488	2/21/1978	Okayama et al.	250	396R	05/19/1976
LN	B	5,298,757	3/29/1994	Okayama	250	396R	02/11/1993

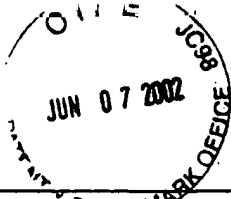
FOREIGN PATENT DOCUMENTS

		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

LN	C	H. SUNAOSHI et al.; "ELECTRON BEAM CALIBRATION METHOD FOR CHARACTER PROJECTION EXPOSURE SYSTEM EX-8D"; Jpn. J. Appl. Phys. Vol 34, pages 6679-6683, Part 1, No. 12 B, 1995.
LN	D	MIYOSHI, M. et al.; "ELECTRON BEAM LITHOGRAPHY SYSTEM AND PATTERN WRITING METHOD"; U.S. Serial No.: 09/624,355, Filed July 24, 2000, Specification 32 pages, and 10 sheets of drawings.

Examiner	<i>Lam Nguyen</i>	<i>6/02/2003</i>
*Examiner:	Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



INFORMATION DISCLOSURE CITATION

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Atty. Docket No.	02087.0208	Serial No.	09/920,633
Applicant	Osamu NAGANO et al.		
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U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate

FOREIGN PATENT DOCUMENTS

Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

LN	Thomson, M. G. R., <i>The electrostatic moving objective lens and optimized deflection systems for microcolumns</i> , 14 J. VACUUM SCI. & TECH. B 3802 (Nov/Dec 1996).

Examiner	<i>Cam/Supu</i>	Date Considered	12/31/2002
*Examiner:	Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		
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